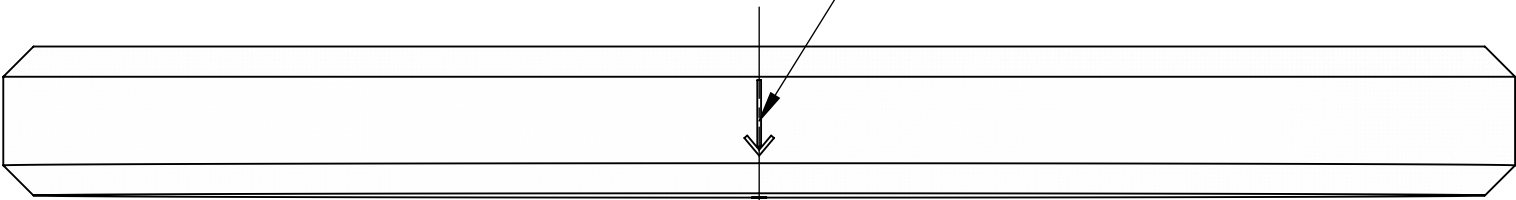
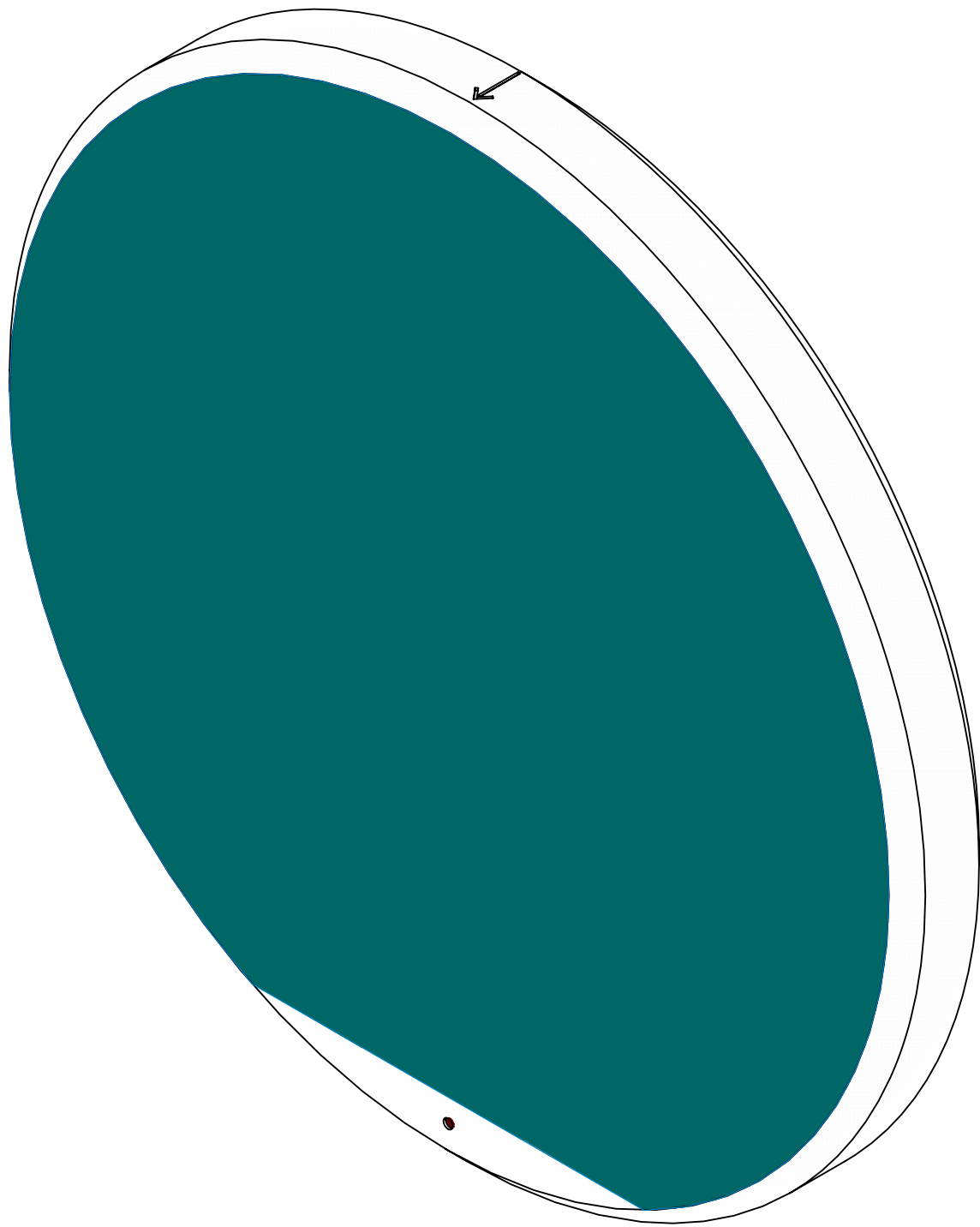


REV.	DATE	DCN #	DRAWING TREE #
v1	01 JUN 2018	E1800165-x0	
-	-	-	
-	-	-	

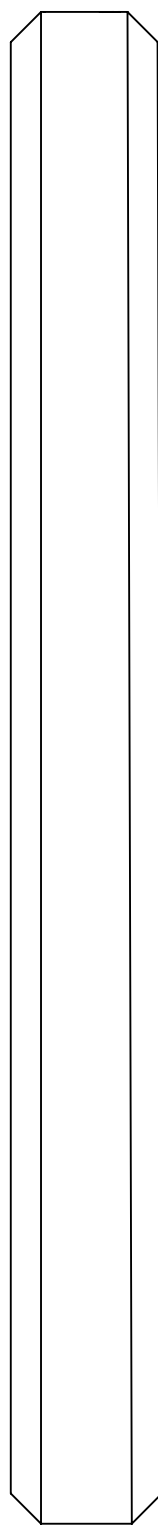
ETCH OR GRIND REGISTRATION MARK
0.25mm±0.05mm WIDE x 5mm±3mm LONG
MINIMUM LEGIBLE DEPTH LINE ALONG ϕ , CENTERED
BETWEEN SURFACES 'S1' AND 'S2' AT
LOCATION OF MINIMUM PART THICKNESS WITHIN
± 5° CLOCKING ANGLE (WITH RESPECT TO DATUM FEATURE -A-)
WITH ARROW POINTING TO SURFACE 'S1'.



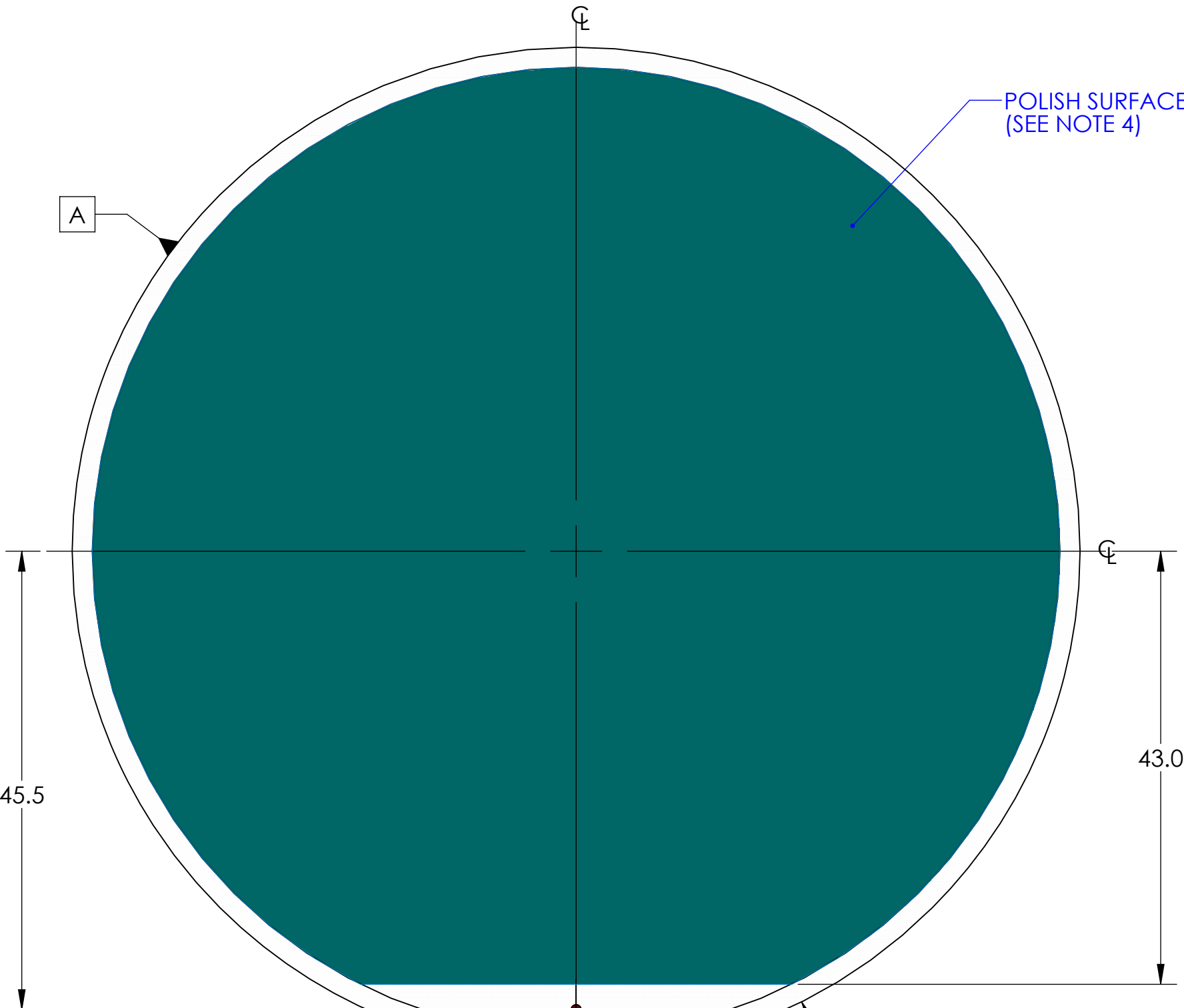
TOP VIEW



ISO VIEW



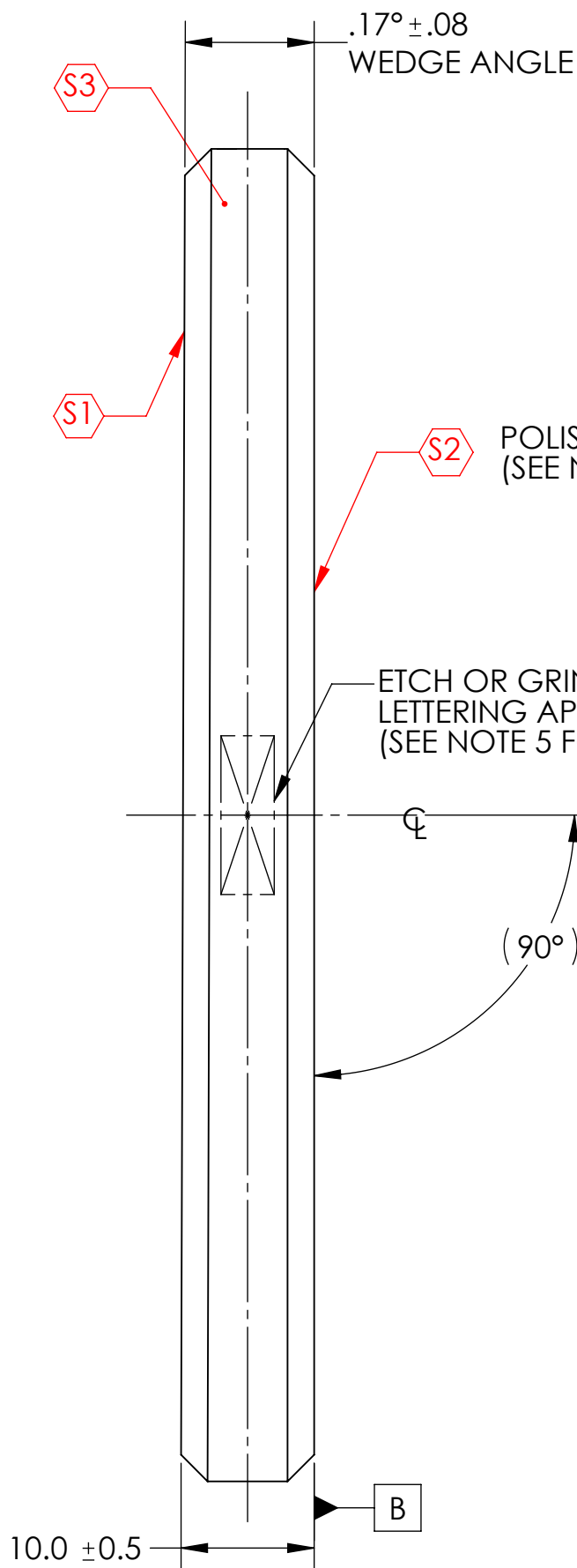
2x 2.0±0.2X45° ±5° CHAMFER,
ALL AROUND



Ø 1.0
SEE NOTE 5

Ø 100.00±0.5
0.1
0.1 B

POLISH SURFACE 'S1'
(SEE NOTE 4)

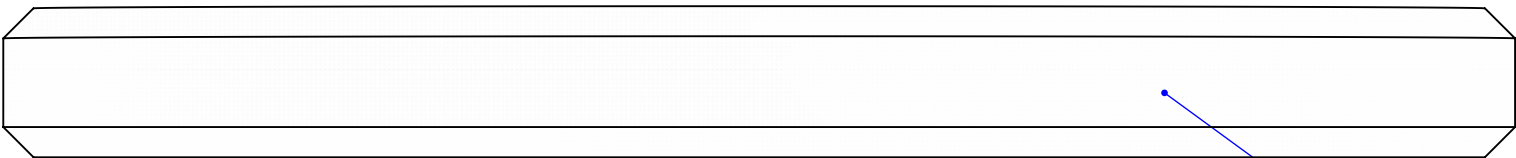


ETCH OR GRIND SERIAL NUMBER, APPROX. WHERE SHOWN,
LETTERING APPROX. 4mm HIGH
(SEE NOTE 5 FOR MORE DETAILS.)

(90°)

.17°±.08
WEDGE ANGLE

POLISH SURFACE 'S2'
(SEE NOTE 4).



BOTTOM VIEW

BARREL SIDE AND BEVEL POLISH
(SEE NOTE 3)

MANUFACTURING NOTES:			
1. DO NOT SCALE FROM DRAWING. 2. INTERPRET DRAWING AS PER ANSI Y14.5M 1994. 3. BARREL SIDE AND BEVEL POLISH PER E1800006-v3. 4. FINISH SURFACES 'S1' AND 'S2' AS PER E1800006-v3. 5. REFER TO E1800006-v3 FOR MORE INFORMATION ON SERIAL NUMBER AND FIDUCIAL MARKING. 6. APPLY COATING PER E1800164.			
PARTS LIST			
NOTES: (UNLESS OTHERWISE SPECIFIED) DIMENSIONS ARE IN MILLIMETERS (mm) TOLERANCES: X ± 0.1 XX ± 0.05 ANGULAR ± 0.1 ° MATERIAL E1800006 FINISH SEE NOTES			
LIGO CALIFORNIA INSTITUTE OF TECHNOLOGY MASSACHUSETTS INSTITUTE OF TECHNOLOGY SYSTEM ADVANCED LIGO SUB-SYSTEM COC NEXT ASSY N/A			
PART NAME 100MM CRYSTALLINE COATING DEMONSTRATION			
NAME E.SANCHEZ	DATE 01/JUN/18	SIZE D	DWG. NO. D1800154
CHECKED SEE DCC	SEE DCC	SCALE N/A	PROJECTION FIRST ANGLE
APPROVED SEE DCC	SEE DCC	SCALE N/A	PROJECTION FIRST ANGLE
			REV. v1
			SHEET 1 OF 1